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Con of Information unless it contains a waid OMS control number. INFORMATION DECLOSURE STATEMENT APPLICANT (Use as many sheets as necessary) Complete if Known **Application Number** 10/786726 February 25, 2004 **Filing Date** First Named Inventor Forbes, Leonard **Group Art Unit** Unknown **Examiner Name** Unknown Attorney Docket No: 303.680US3 Sheet 1 of 3

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Group Art Unit	Unknown		
First Named Inventor	Forbes, Leonard		
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	First Named Inventor	Forbes, Leonard		
	Group Art Unit	Unknown		
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